

ABSTRACT

The present disclosure describes a substrate processing apparatus, a method of replacing a processing tool, and a replacement tool that can efficiently replace a processing tool with a simple configuration.

5 A substrate processing apparatus includes: a holding unit; a rotating unit configured to rotate the holding unit; a processing tool configured to process a surface of a substrate held by the holding unit; a replacement tool configured to be detachably attached to the holding unit; a holding and transport unit configured to hold and transport the
10 processing tool; and a control unit. The replacement tool includes; a main body configured to be engageable with an engagement part of the processing tool; and a flange portion projecting from a peripheral surface of the main body for attachment to and detachment from the holding unit. The control unit is configured to execute a first process of attaching and
15 detaching the processing tool to and from the holding and transport unit by controlling the rotating unit to rotate the holding unit in a state where the replacement tool is attached to the holding unit via the flange portion and the engagement part of the processing tool is engaged with the main body of the replacement tool.

20 FIG. 7